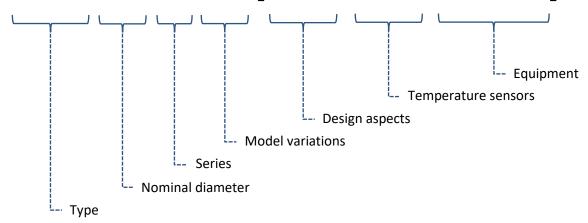


# **VELCO 500 H2 N80 [KXGX-S1S18-XXX1DM]**



#### Type and nominal diameter - VELCO 500 H2 N80

Туре	
VELCO	≥ DN 250 / Generation 1
VELCO <sup>2</sup>	≥ DN 250 / Generation 2
VCP	≤ DN 200 / cold head 90° to flange

Standard nominal diameter	
DN 100	DN 500
DN 160	DN 630
DN 200	DN 800
DN 250	DN 900
DN 320	DN 1000
DN 400	DN 1250

#### Series and special model - VELCO 500 H2 N80 (optional)

Series	
S	Sputtering process with argon, T1 limitation (memory effect), and wide baffle for process pressures up to 5E-3 mbar.
Xe	For processes involving Xenon, a special configuration allows pumping of Xe at <50K on the first stage.
LN2	The first stage is operated with liquid nitrogen. The second stage is operated with a GM cooling system.
H2	Optimized for hydrogen as process gas. Special models for pumping speed and throughput.
LV	Low vibration. Pulse tube cooling system and additional measures to minimize vibrations.
UHV	All metal sealed and heatable in various stages for UHV applications.
Kr	For processes involving Krypton, a special configuration allows pumping of Kr at <37K on the first stage.

Model variations		
N	One or two letters are used to declare cooling system options deviating from the standard.	
80	This number describes the lowest temperature resistance of the components used. (without displacer)	

HSR AG - 23.01.2024 Page 1 / 2



## Design [KXGX-S1S18-XXX1DM]

		_		
Flange			Ηοι	using material
K	ISO-K		Х	1.4301
F	ISO-F		L	1.4404
С	CF-F		Α	3.2315
Α	ASA			
٧	Vinyl			

Ηοι	using model
G	Standard
F	Flange without housing
С	Housing all flanges CF-sealed, cold head with edge sealing
0	Housing all flanges CF-sealed, cold head with o-ring
U	Housing all flanges CF-sealed, cold head CF-sealed
W	Housing water-cooled and O-ring sealed
Z	Housing water-cooled and CF-sealed

Che	emical resistance
Х	Standard
K	Corrosive media
R	Radiation
Т	Tritium
М	Resistant to metallic coating
Υ	T + No fluorine and chlorine-containing components

## Temperature sensors [KXGX-S1S18-XXX1DM]

Type stage 1		
Х	none	
S	KTS standard	
K	KTS slightly corrosive	
D	KTS highly corrosive	
Р	KTP PT sensor	
С	KTC Cernox	
	encapsulated	
Υ	KTC Cernox exposed	
L	KTD diode DT670	
U	Diode SI-410	

No.	
Χ	
1	
2	
3 4	
4	

Тур	e stage 2
Х	none
S	KTS standard
K	KTS slightly corrosive
D	KTS highly corrosive
Р	KTP PT sensor
С	KTC Cernox
	encapsulated
Υ	KTC Cernox exposed
L	KTD diode DT670
U	Diode SI-410

Fe	edthrough
5	5-pin CF-F Vacom
8	8-pin ISO-K Lemo
S	5-pin CF-F Sumitomo

### Options [KXGX-S1S18-XXX1DM]

Valve		
Х	none	
Р	AVC 040	
В	UHV GE41	

Pur	ge gas
Х	none
٧	N.C.
Ν	N.O.

Heater		
Х	none	
Н	Heating jacket	
D	HDL	
S	HDH	

No. HCH
X
1
2

X none P PKR 251 T PIT 104 D 2x CCT 36x R TPR 018 G PSG 500 C 2x CDG025	Pressure gauge		
T PIT 104 D 2x CCT 36x R TPR 018 G PSG 500 C 2x CDG025	Х	none	
D 2x CCT 36x R TPR 018 G PSG 500 C 2x CDG025	Р	PKR 251	
R TPR 018 G PSG 500 C 2x CDG025	Т	PIT 104	
G PSG 500 C 2x CDG025	D	2x CCT 36x	
<b>C</b> 2x CDG025	R	TPR 018	
2 2 2 2 2 2 2 2	G	PSG 500	
II CDC100D	С	2x CDG025	
u CDG100D	Н	CDG100D	

Electronics		
X	none	
Т	TPM	
С	CBO	
M	T + C	

HSR AG - 23.01.2024 Page 2 / 2